

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	5307	porous adj silicon	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/06/06 13:34
L2	378399	((("257") or ("438"))).CLAS.	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/06/06 13:35
L3	1838	l1 and l2	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/06/06 13:35

- ✎ S5: (1946) (pressure adj sensor) with (porous porosity bubble cavity void microporous nanoporous)
- ✎ S6: (250) S5 and ((pressure adj sensor) with semiconductor)
- ✎ S7: (17) S6 and (parallel perpendicular\$2) with (porous porosity bubble cavity void microporous na...
- ✎ S8: (2) S6 and (parallel perpendicular\$2) with ((porous porosity bubble cavity void microporous na...
- ✎ S9: (1751) S5 and ((pressure adj sensor) with (hollow cavity))
- ✎ S10: (701) S9 and layer
- ✎ S11: (452) S10 and silicon
- ✎ S12: (420) S11 and first
- ✎ S13: (404) S12 and second
- ✎ S14: (95) S13 and (structure near3 (porous porosity bubble cavity void microporous nanoporous))
- ✎ S15: (1) 10/655,839
- ✎ S16: (2581) (pressure adj sensor) with (hollow cavity pocket)
- ✎ S17: (2470) (pressure adj sensor) with (hollow cavity )
- ✎ S18: (666) (pressure adj sensor) with (hollow )
- ✎ S19: (1886) (pressure adj sensor) with (cavity )
- ✎ S20: (1897) S16 and (pressure adj sensor) with (porous porosity bubble cavity void microporous nan...
- ✎ S21: (299) S20 and (pressure adj sensor) with (layer film near4 (porous porosity bubble cavity voi...
- ✎ S22: (299) S21 and (pressure adj sensor layer film porous porosity bubble cavity void microporous...
- ✎ S23: (269) S22 and first
- ✎ S24: (257) S23 and second
- ✎ S25: (10) 9 and (pressure adj sensor) with (porous porosity void microporous nanoporous)
- ✎ S26: (2186) (amorphous) near4 (porous porosity void microporous nanoporous)
- ✎ S27: (1318) (amorphous) near2 (porous porosity void microporous nanoporous)
- ✎ S28: (1080) (amorphous) near2 (porous )
- ✎ S29: (694) (amorphous) near (porous )
- ✎ S30: (1) (amorphous near porous) with sensor
- ✎ S31: (10145) (sensor) near5 (hollow cavity )

S20 and  
((pressure adj  
sensor) with  
(layer film near4  
(porous porosity  
bubble cavity void  
microporous  
nanoporous))

S20 and  
((pressure adj  
sensor) with  
(layer film near4  
(porous porosity  
buble cavity void  
microporous  
nanoporous))